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OBJECTIVE

Looking for an exciting career opportunity in plasma processing R&D

EDUCATION

1999-Present

Graduate Student / Research Assistant, PhD (Electrical Engineering, expected 08/02), ECE Department, Plasma Engineering Lab, Northeastern University, Boston, MA 02115. Advisor: Prof. J. A. Hopwood.

"Micro Inductively Coupled Plasma Chamber Design for Efficient Optical Emission Detection of SO₂"

1996-1999

Graduate student / Research Assistant, MS (Physics, 08/99), Physics Department & Texas Center for Superconductivity at the University of Houston, Houston, TX 77004-5932. Advisor: Prof. W.-K. Chu

"High Resolution Depth Profiling by ¹⁸O(p,α)¹⁵N Nuclear Reaction for Oxygen Self-diffusion Study in Ionic Conducting Materials"

1993-1995

Graduate student, MS (Mechanical Engineering/ Material Science, 08/95), Machine-building technology department, Ufa State Aviation Technical University, Ufa, Russia, 450025. Advisor: Prof. V.V. Budilov

"Research and Development of Technology of Ion Modification and Ion Assisted Deposition of TiN Coating onto Stage II Aircraft Engine Compressor Blades"

1988-1993

BSME (GPA 4.0), Diploma with Honor, Machine-building technology department, Ufa State Aviation Technical University, Ufa, Russia, 450025.

LANGUAGE AND COMPUTER SKILLS

Native language - Russian. Proficient in English.

Working knowledge of MS Word, MS Excel, Axum, Mathcad, Origin, TSUPREM, computer simulation programs for ion beam techniques (TRIM, RBX, GRACES, VRBS)

RESEARCH EXPERIENCE

Proficient in material science, plasma processing, mechanical engineering, and nuclear physics.

Experienced in analysis techniques (RBS/Channeling, NRA, ERD, PIXE, atomic emission spectroscopy), ion beam assisted deposition, protective coatings, corrosion and wearing mechanisms, material modification (doping, mixing by ion implantation), microfabrication processes (wafer cleaning, sputtering deposition, photolithography, Au electroplating, RIE, ICP etching, wafer dicing, wire bonding).

1995-1996

Research visitor, Texas Center for Superconductivity at the University of Houston, Houston TX 77004

1993-1995

Summer Intern, Material Processing Lab, Ufa Engine Industrial Association, Ufa, Russia

HONORS

1995-1996 Scholarship of the President of Russian Federation for studying abroad

1995 First prize, International Graduate Student Symposium for Innovations in Space and Aviation Technology, Moscow, Russia

1991-1993 Member of the Board (Student Representative) of Ufa State Aviation Technical University

PUBLICATIONS

J. Hopwood, O. Minayeva, and Y. Yin, "Fabrication and characterization of a 5-mm inductively coupled plasma generator," *Journal of Vacuum Science and Technology B*, **18** (5), 2446-2451 (2000)

J. R. Liu, O. Minayeva, W. K. Chu, "Cross section for Non-Rutherford backscattering of α on ¹⁰B," CP392, Application of Accelerators in Research and Industry, L.Duggan, I.Morgan eds., *AIP Press*, 627-630 (1997)

O.B. Minayeva, "Engineering technique for deposition parameters calculation of vacuum ion assisted plasma coatings for the setups with planar cathode configuration," Russian patent #950243, July 1995

V.V. Budilov, V.S. Mukhin, O.B. Minayeva, "Mathematical modeling of the deposition process of vacuum ion assisted plasma coatings," *Russian Aeronautics*, **1**, 92-95 (1995)